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(54) **MANUFACTURING MEDICAL DEVICES BY VAPOR DEPOSITION**

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(57) **ABSTRACT**

A method of forming a medical device, the method including the steps of providing a substrate, depositing a metallic layer on the substrate by a vapor deposition process, and removing the metallic layer from the substrate. The metallic layer thus removed is the medical device or serves as a basis for forming the medical device. In another aspect, the present invention includes a medical device formed by the process of the present invention.